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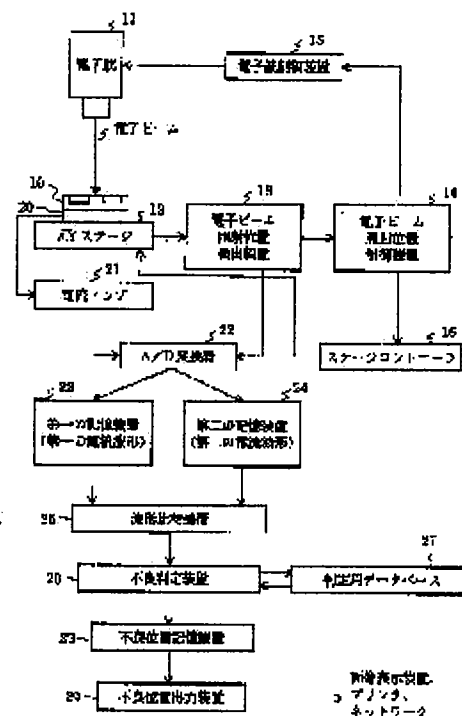
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(54) METHOD AND EQUIPMENT FOR INSPECTING DEVICE

(57)Abstract:

PROBLEM TO BE SOLVED: To obtain correct inspection results without using any CAD data, even in the case that holes like a logic circuit are arranged at random, when the conforming/nonconforming inspection of a device is performed by using current generated due to electronic beam irradiation in a specimen to be inspected.

SOLUTION: An electron beam is applied onto the specimen to be inspected while it is scanned, a current value generated in the specimen corresponds to the irradiation position of the electron beam at the time when the electron beam is applied, stored as a current waveform, and an incorrect position is detected by comparing the current waveforms of the two inspection specimens.



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